

**Amendments to the Abstract**

Please replace the Abstract Of The Disclosure with the following:

**Abstract Of The Disclosure**

The present invention generally relates to an apertured or reticulated film, and more specifically, the present invention relates to a method of imparting one or more raised elements into a previously apertured or reticulated film utilizing a forming surface. A forming apparatus can accept an apertured film, preferably but not limited to a thermoplastic composition, and impart one or more raised continuous or discontinuous profiled elements into the surface of the apertured film by exposing the apertured film to an air stream having an elevated temperature (such as by exposure of the air stream to direct contact with a heating element). The heated air stream affects the apertured film by inducing the film to deflect onto profiled elements defined in the forming surface of the forming apparatus.